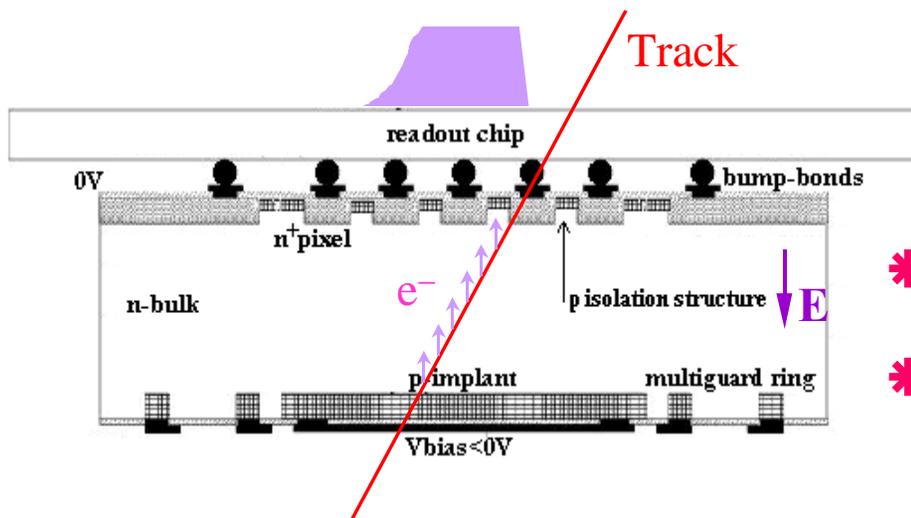


MC Simulation of Silicon Pixel Detector

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Readout Signal Simulation



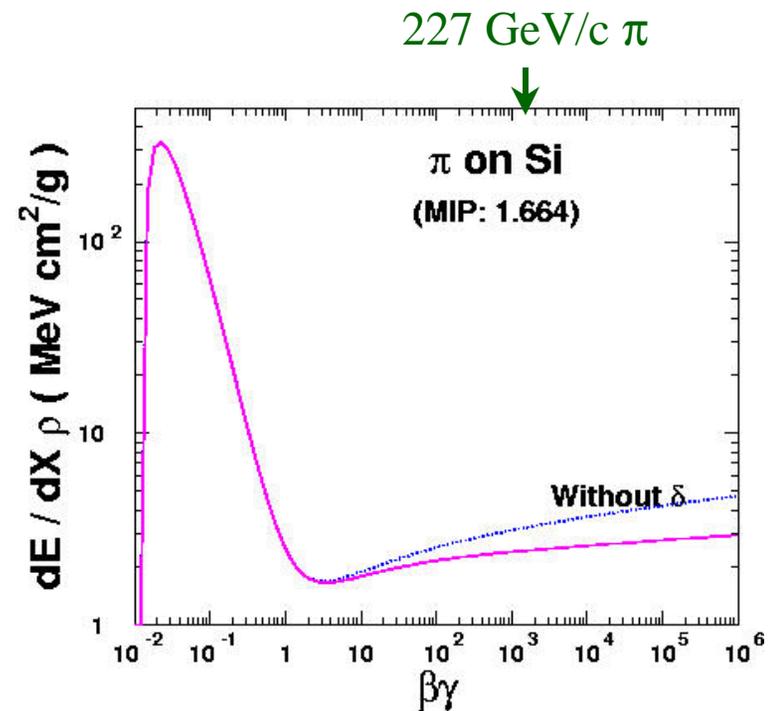
- * Energy deposition by charged track along its path length, and production of electron/hole pairs
- * Electron clouds drifting towards readout pixel in electric field (corresponding to doping and bias voltage applied)
- * Electron cloud spread due to diffusion
- * Magnetic field deflection (our sensors will be in dipole field of 1.6 T)
- * Realistic front end electronics (noise, threshold, digitization accuracy)

Energy Deposition

$$\frac{dE}{\rho dx} = 2\pi N_{Av} r_e^2 m_e c^2 \frac{Z}{A} \frac{1}{\beta^2} \left[\ln \frac{2m_e c^2 \beta^2 \gamma^2 T_{max}}{I^2} - 2\beta^2 - \delta \right]$$

$$\xi = 2\pi N_{Av} r_e^2 m_e c^2 \frac{Z}{A} \frac{1}{\beta^2} \cdot \rho \cdot \delta x$$

- ◆ Density effect: δ
- ◆ At high $\beta\gamma$, radiative losses need to be considered (+7%)
- ◆ Thin material (280 μ m silicon):
 $\xi = 5.0 \text{ keV}, \quad \xi / I_0 = 29$



Production of δ -ray

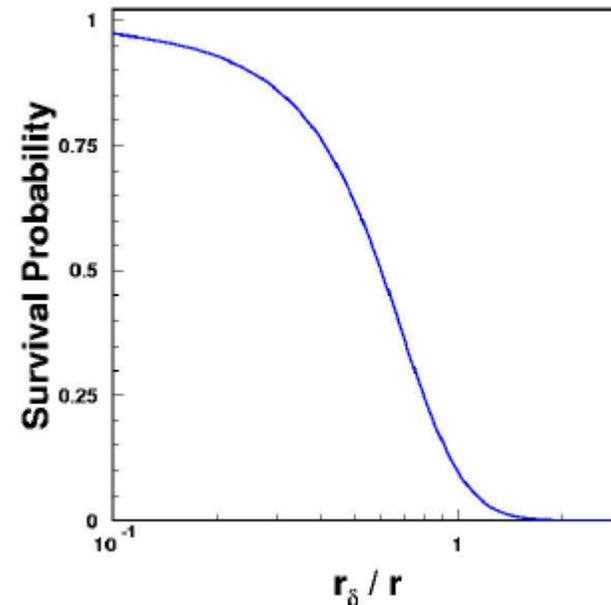
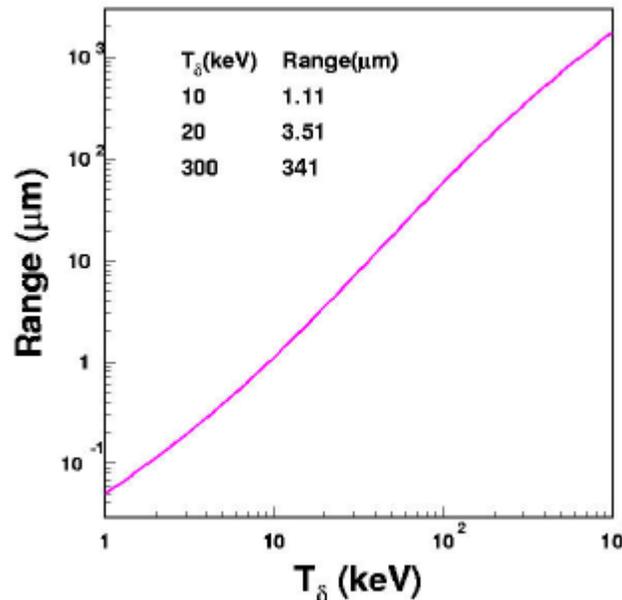
$$\frac{dN}{dT \cdot dx} = \left(\rho \cdot 2\pi N_{\text{Av}} r_e^2 m_e c^2 \frac{Z}{A} \right) \times \frac{1}{\beta^2} \cdot \frac{1}{T^2} \left(1 - \beta^2 \frac{T}{T_{\text{max}}} \right)$$

$$\cos^2 \theta = \frac{T}{T + 2m_e} \bullet \frac{T_{\text{max}} + 2m_e}{T_{\text{max}}}$$

- ◆ Number of δ -ray: $\langle N \rangle \approx 0.5$ ($T_{\text{cut}}=10$ keV, $d=280$ μm)
- ◆ Kinetic energy according to dN/dT
- ◆ Polar angle θ is calculated
- ◆ Azimuthal angle ϕ generated isotropically

Ionization of δ -ray

- The δ -ray range is calculated
- The length of δ -ray \leftarrow Survival probability function
- Ionization uniformly
- δ -ray escape (only 1/4 of energy collected)



Excitation and Ionization

▣ Urbán model (thin material: $\xi/I = 29$ for 280 μm silicon)

▣ Excitations: E_1 E_2 Ionization: E_3

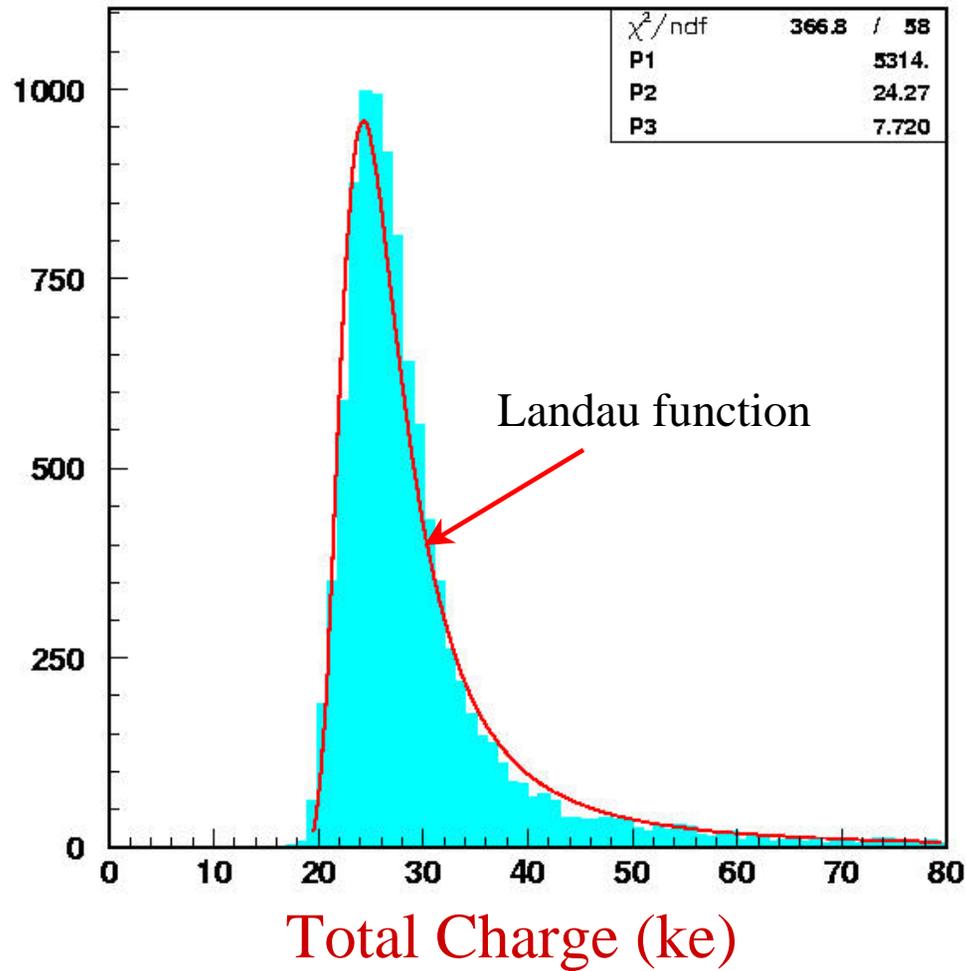
$$\begin{aligned} E_2 &= 10 \cdot Z^2 \text{eV} \\ E_1 &= \left(I / E_2^{f_2} \right)^{1/f_1}, \quad f_2 = 2/Z, \quad f_1 = 1 - f_2 \\ g(E_3) &\propto 1 / E_3^2, \quad I < E_3 < E_{\text{max}} \end{aligned}$$

▣ Cross-sections

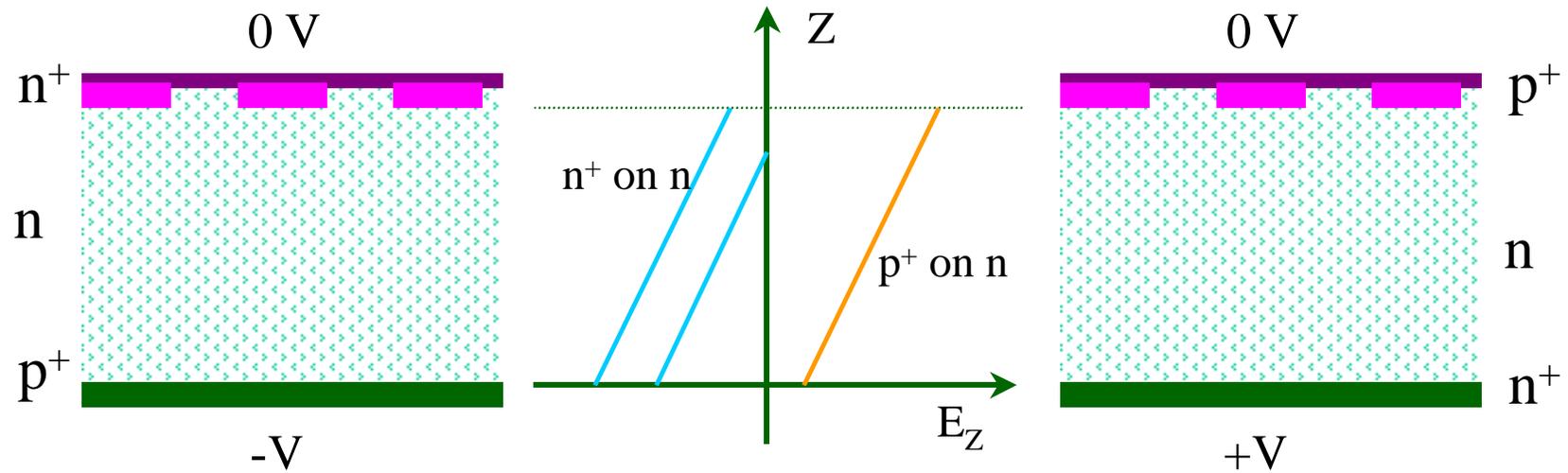
$$\begin{aligned} \Sigma_i &= C \cdot (1 - r) \cdot \frac{f_i}{E_i} \cdot \frac{\ln(2m\beta^2\gamma^2 / E_i) - \beta^2}{\ln(2m\beta^2\gamma^2 / I) - \beta^2} \\ \Sigma_3 &= C \cdot r \cdot \frac{E_{\text{max}}}{I(I + E_{\text{max}}) \cdot \ln(E_{\text{max}} / I + 1)} \end{aligned}$$

▣ dE/dx : $C \cdot (1-r)$ for excitation and $C \cdot r$ for ionization

Total Charge



Electric Field



$$|E_z| = \frac{V}{d} \mp \frac{(2Z - d)V_D}{d^2}$$

Mobility

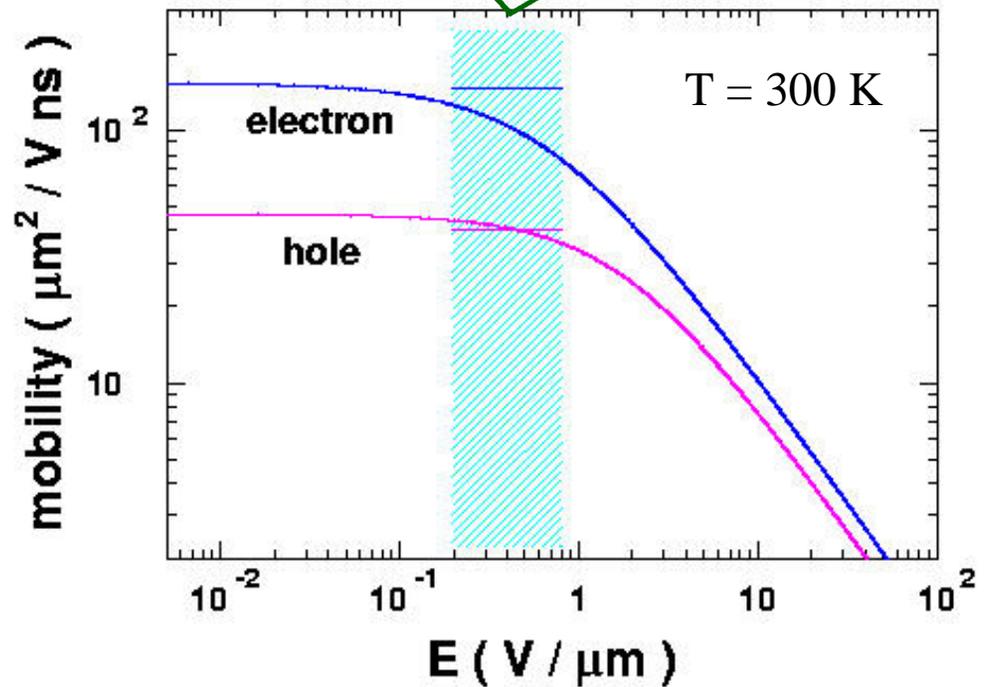
$$\mu = \mu_0 / \left(1 + \left(\frac{E}{E_C} \right)^\beta \right)^{1/\beta}$$

$$\mu_0^n = 153.3 \cdot \left(\frac{T}{300} \right)^{-2.42} \mu\text{m}^2 / \text{V} \cdot \text{ns}$$

$$E_C^n = 0.698 \cdot \left(\frac{T}{300} \right)^{1.55} \text{V} / \mu\text{m}$$

$$\beta^n = 1.109 \cdot \left(\frac{T}{300} \right)^{0.66}$$

$$\begin{aligned} V_{\text{applied}} &= 140 \text{ V} \\ V_{\text{depletion}} &= 85 \text{ V} \\ d &= 280 \mu\text{m} \end{aligned}$$



Magnetic Field

$$\vec{E} = E \cdot \vec{e}_Z, \quad \vec{B} = B_X \cdot \vec{e}_X + B_Y \cdot \vec{e}_Y + B_Z \cdot \vec{e}_Z$$

$$V_Z = \frac{1 + \mu_H^2 B_Z^2}{1 + \mu_H^2 B^2} \cdot \mu E = \mu_{\text{eff}} E \quad \mu_H = \begin{cases} 1.15 \cdot \mu & \text{electron} \\ 0.72 \cdot \mu & \text{hole} \end{cases}$$

$$\tan \vartheta_X = \frac{B_X B_Z \mu_H^2 \pm \mu_H B_Y}{1 + \mu_H^2 B_Z^2} \quad \tan \vartheta_Y = \frac{B_Y B_Z \mu_H^2 \mp \mu_H B_X}{1 + \mu_H^2 B_Z^2}$$

Charge Cloud Spread

- Radius of ionization trail:

$$R = \hbar c \beta \gamma / I \quad (\sim 2\mu\text{m})$$

- Diffusion:

$$D = kT\mu / q, \quad \sigma_X = \sigma_Y = \text{sqrt}(2Dt)$$

Electronics

- Noise (preamplifier, ADC)
- Non-uniform threshold
- Gain uncertainty
- ADC precision

Cluster Algorithm

- Similar as test beam offline analysis
- Plan: study overlapped cluster
- This might also improve the resolution by reducing the effect of δ -ray

Charge Sharing

Fraction of Cluster (row) size

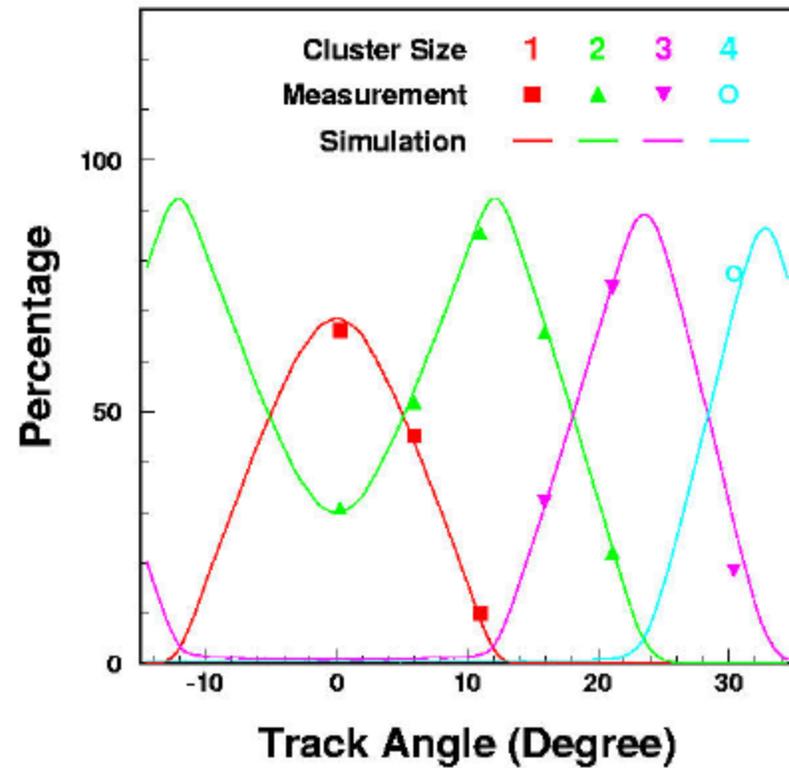
Measurement

Angle	Size 1	Size 2	Size 3	Size 4	Size ≥ 5
0°	.665	.311	.012	.006	.006
5°	.452	.518	.016	.006	.008
10°	.099	.857	.028	.007	.009
15°	.001	.658	.320	.010	.011
20°	.000	.221	.746	.019	.014
30°	.000	.000	.185	.775	.040

Simulation

Angle	Size 1	Size 2	Size 3	Size 4	Size ≥ 5
0°	.684	.300	.009	.004	.003
5°	.436	.547	.010	.004	.003
10°	.087	.886	.017	.005	.005
15°	.000	.676	.312	.006	.006
20°	.000	.229	.754	.010	.007
30°	.000	.000	.279	.704	.017

FPIX0 CiS p-stop $Q_{th} = 2500 e^-$
 $V_{bias} = -140V$ $V_{depl} = -85V$

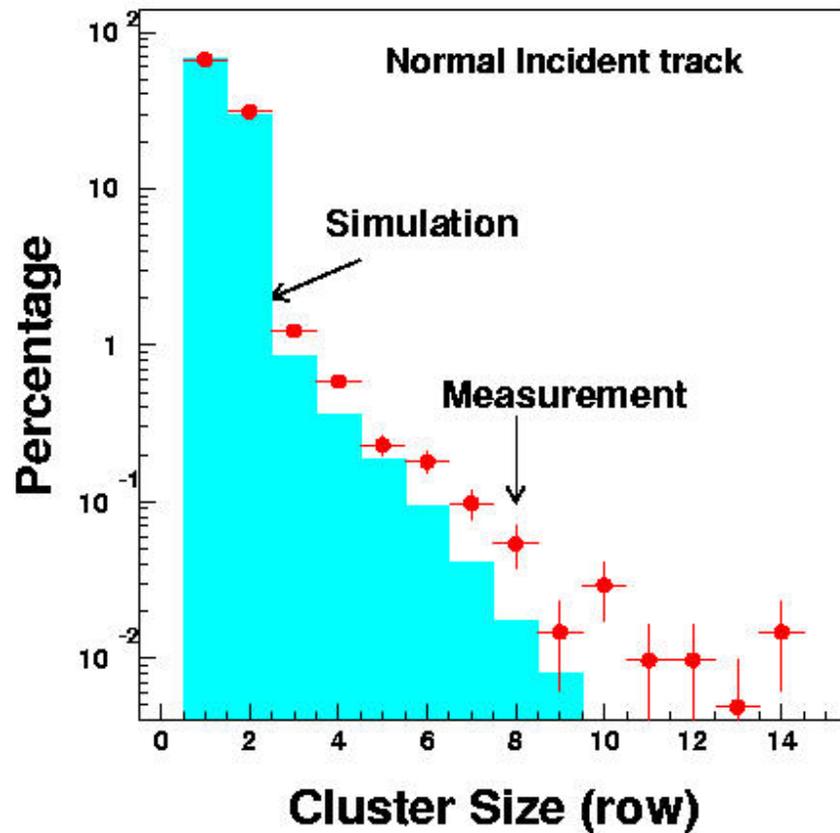


Large Size Cluster

Simulation has less
large size cluster than
measurement

Source ?

FPIX0-pstop



Charge Sharing

Fraction of Cluster (row) size

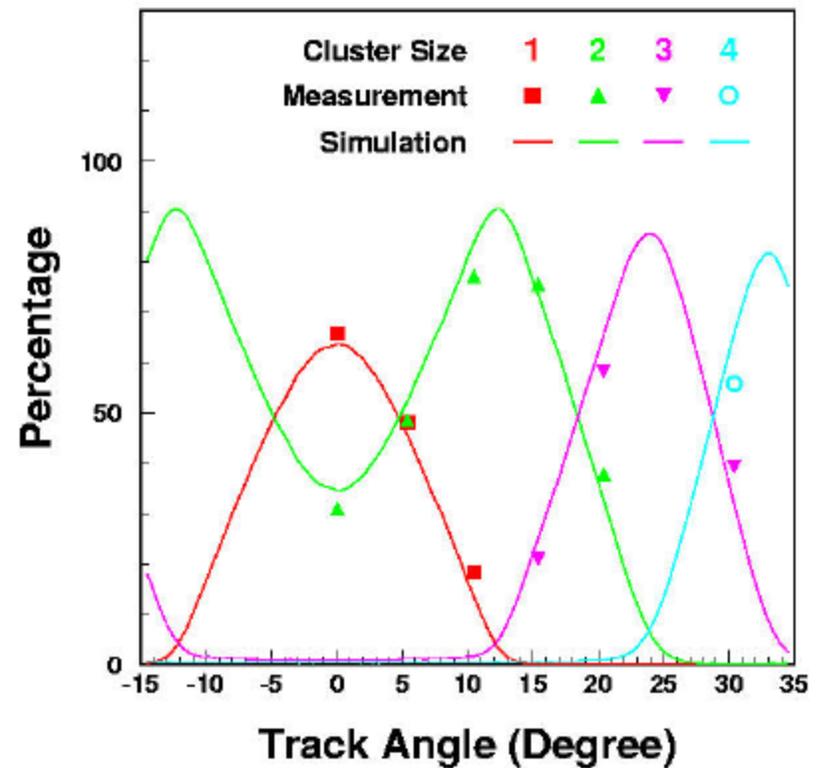
Measurement

Angle	Size 1	Size 2	Size 3	Size 4	Size ≥ 5
0°	.660	.311	.016	.006	.007
5°	.482	.486	.018	.007	.007
10°	.183	.771	.028	.008	.009
15°	.012	.756	.211	.010	.011
20°	.006	.379	.582	.018	.015
30°	.006	.011	.393	.558	.032

Simulation

Angle	Size 1	Size 2	Size 3	Size 4	Size ≥ 5
0°	.636	.346	.009	.004	.005
5°	.456	.525	.011	.004	.004
10°	.135	.838	.017	.005	.005
15°	.002	.736	.250	.006	.006
20°	.000	.328	.654	.010	.008
30°	.001	.002	.320	.657	.020

FPIX1 Seiko p-stop $Q_{th} = 3780 e^-$
 $V_{bias} = -75V$ $V_{depl} = -45V$

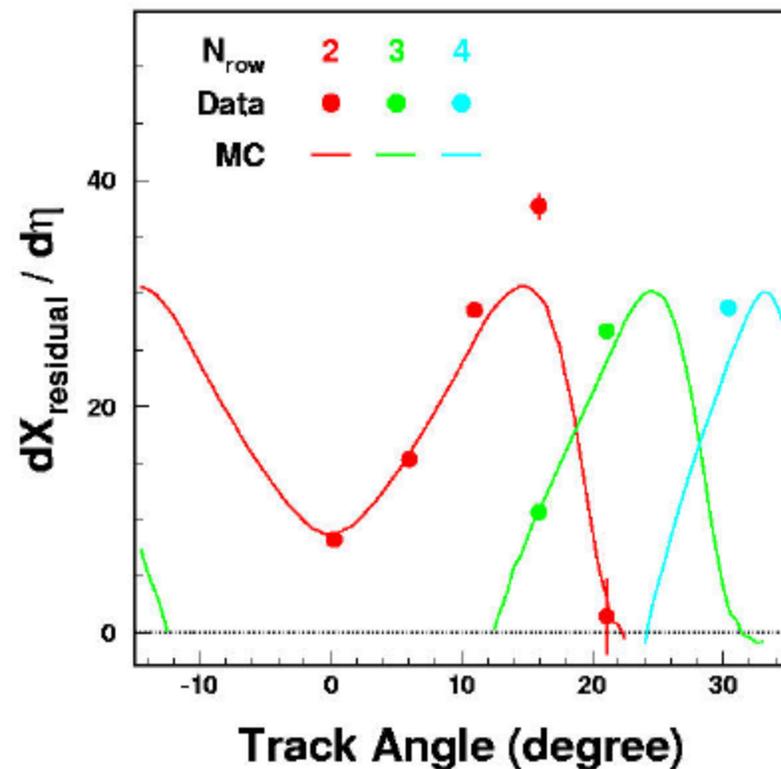


Reconstruction

Linear η correction applied

$$X_{\text{residual}} = X_{\text{track}} - X_{\text{recon}}$$

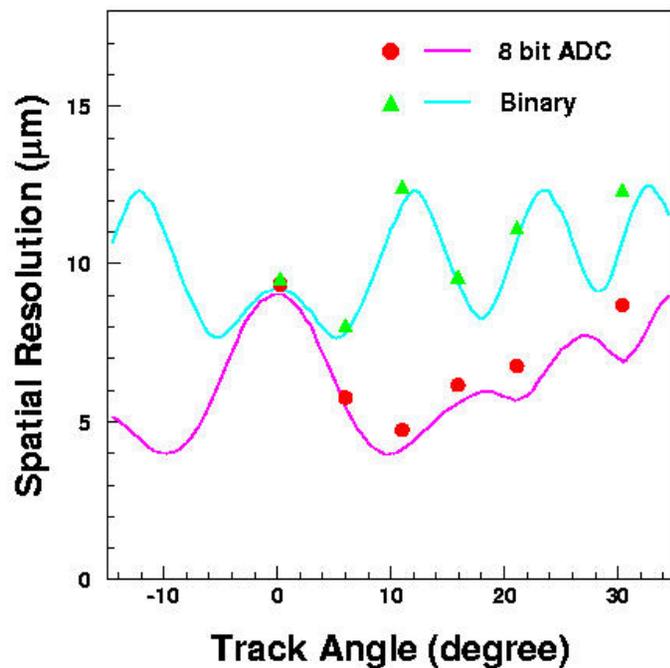
$$\eta = \frac{Q_{\text{right}} - Q_{\text{left}}}{Q_{\text{right}} + Q_{\text{left}}}$$



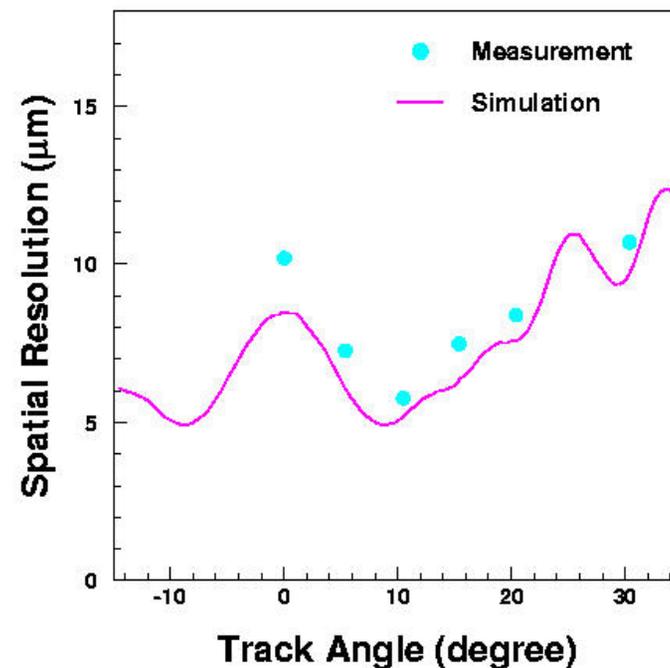
Resolution vs angle

- ★ No track projection error subtracted from the measurement
- ★ Resolution distribution agrees with simulation
- ★ Binary resolution degraded from 8-bit ADC

FPIX0 p-stop



FPIX1 p-stop



Summary

- New version simulation program works quite well
- There are not much can be tuned
- Plug the code into BTeV simulation
- Two approaches need to be evaluated
 - Use GEANT simulation in energy deposition
 - Use the energy deposition simulation of this program

Beam Test Track Angle

Angle ($^{\circ}$)	FPIX0 p-stop	FPIX0 p-spray	FPIX1 p-stop	FPIX1 p-spray
0 $^{\circ}$	0.25	0.00	0.02	N/A
5 $^{\circ}$	6.00	5.33	5.42	5.33
10 $^{\circ}$	10.99	10.24	10.49	10.27
15 $^{\circ}$	15.88	16.64	15.40	15.19
20 $^{\circ}$	21.06	21.57	20.40	N/A
30 $^{\circ}$	30.37	31.48	30.42	N/A

Precision of the alignment is about 0.1 $^{\circ}$

(i.e. Four runs of FPIX1 P-spray at 15 $^{\circ}$: *15.16, 15.22, 15.25, 15.16*)